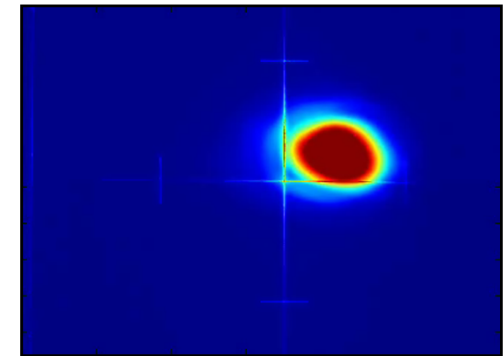


Notes on Requirements for cathodes from a SC Linac driven FEL

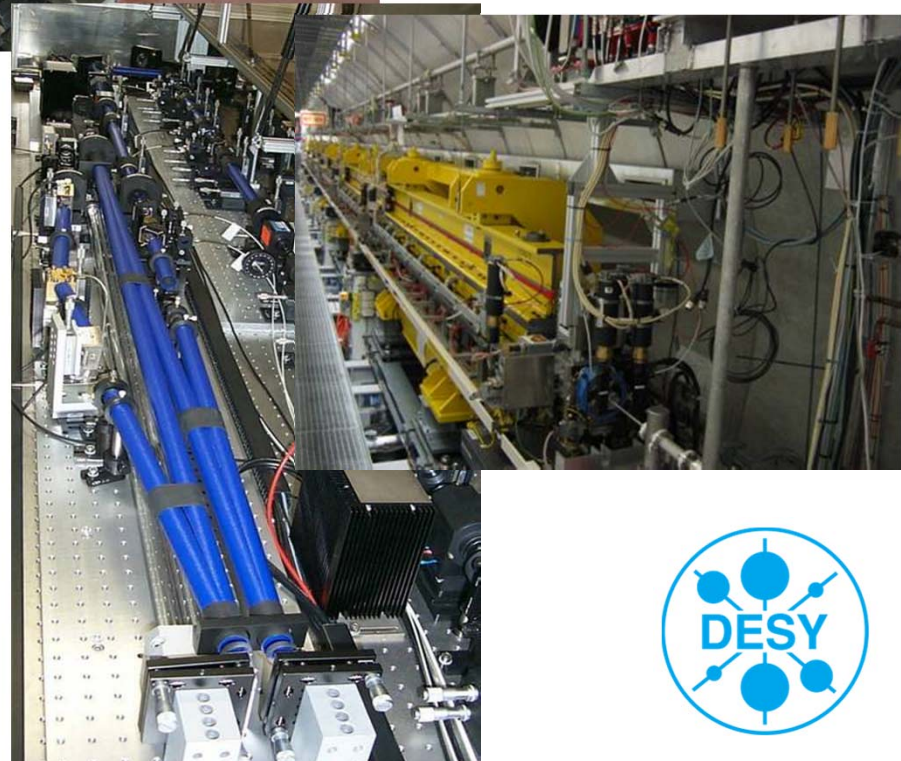
Siegfried Schreiber
DESY



EUROFEL Workshop on Photocathodes
for RF guns

WG2

March 2, 2010
Lecce, Italy



Light Sources

We talk about new generation light sources:

- > X-ray single pass FELs → hundreds of pulses per second
- > X-ray single pass FELs operated in burst mode
→ thousands of pulses per second
- > X-ray ERLs → quasi cw operation with many thousands of pulses per second

Parameters:

- > Aim for high peak and average brilliance of X-ray radiation
 - High peak brilliance → beam quality
 - High average brilliance → high beam current or many bunches/second

All light sources need electron sources

→ high quality and/or high average power systems



Parameter Spaces

> Low repetition rate machines

- LCLS
- Spring8 XFEL
- Fermi@Elettra
- SparcX
- SwissFEL

> Burst mode machines

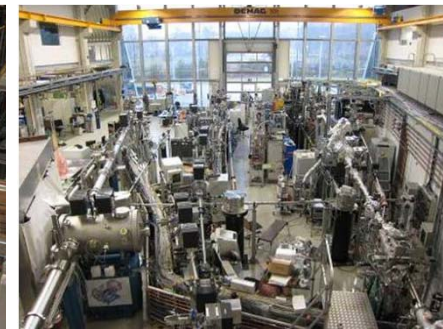
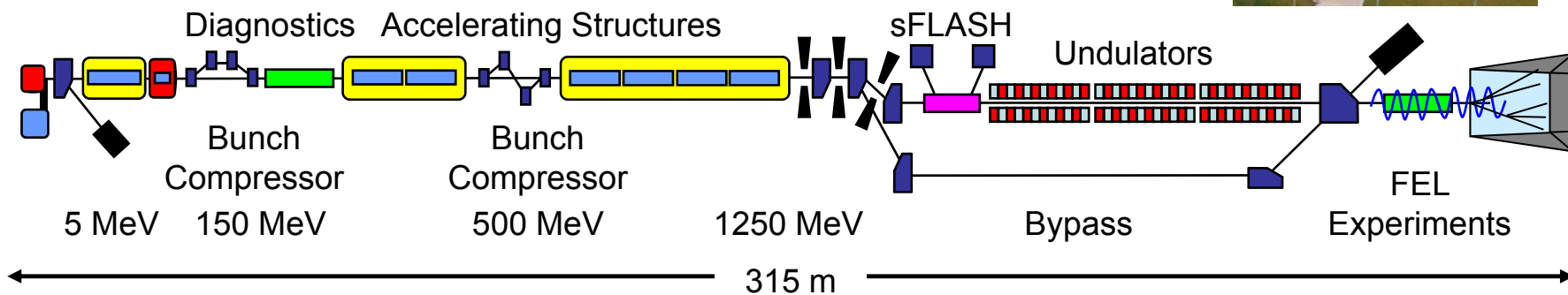
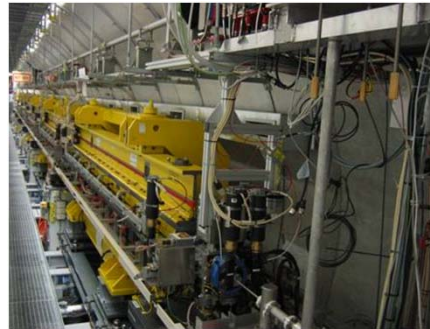
- European XFEL
- FLASH

> High repetition rate machines

- NLS
- WIFEL
- BerlinPro ERL
- Cornell ERL

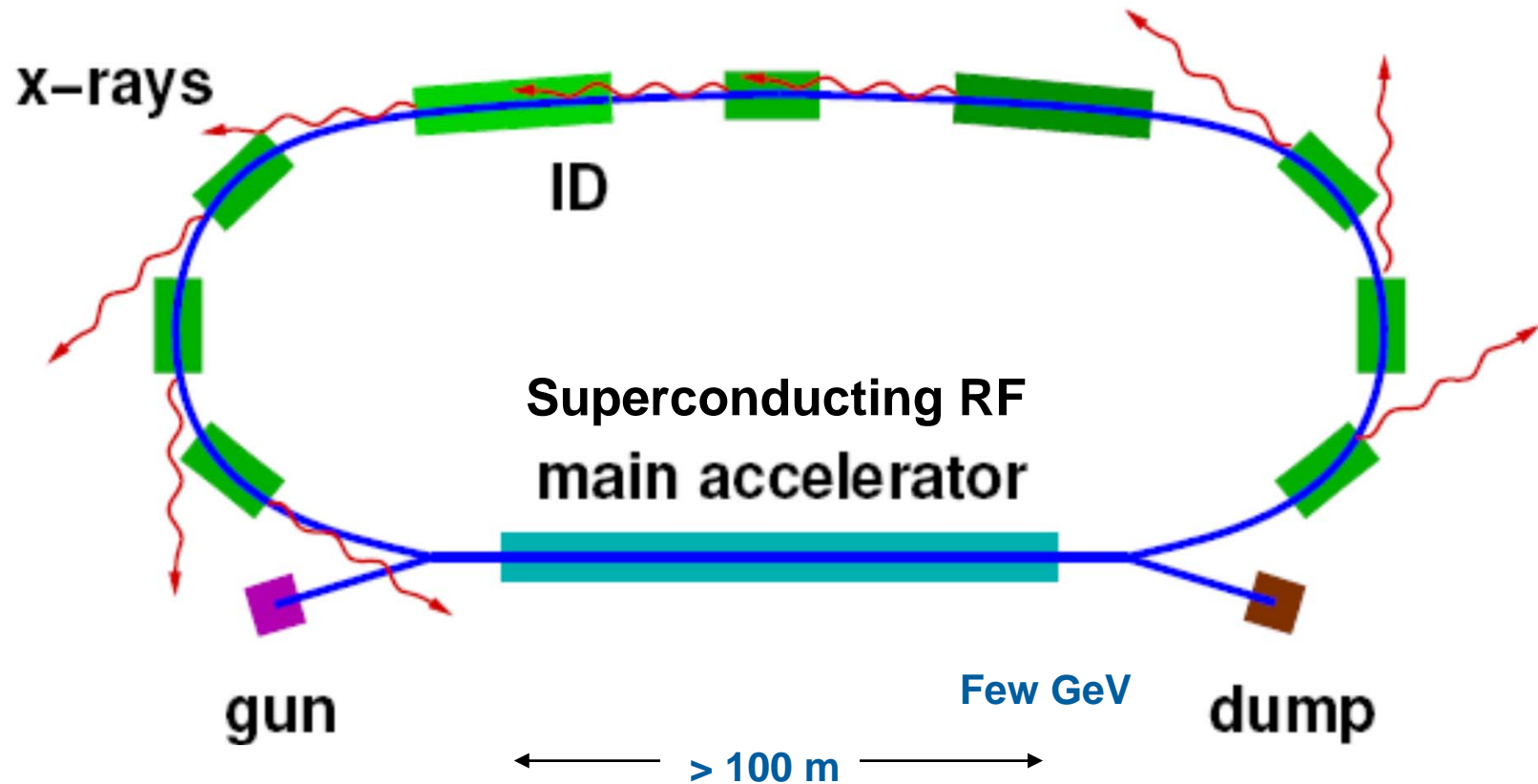


FLASH – operates in burst mode



ERL – Energy recover linac

- > Energy recovery to reach high average power



Bunch Pattern – typical examples

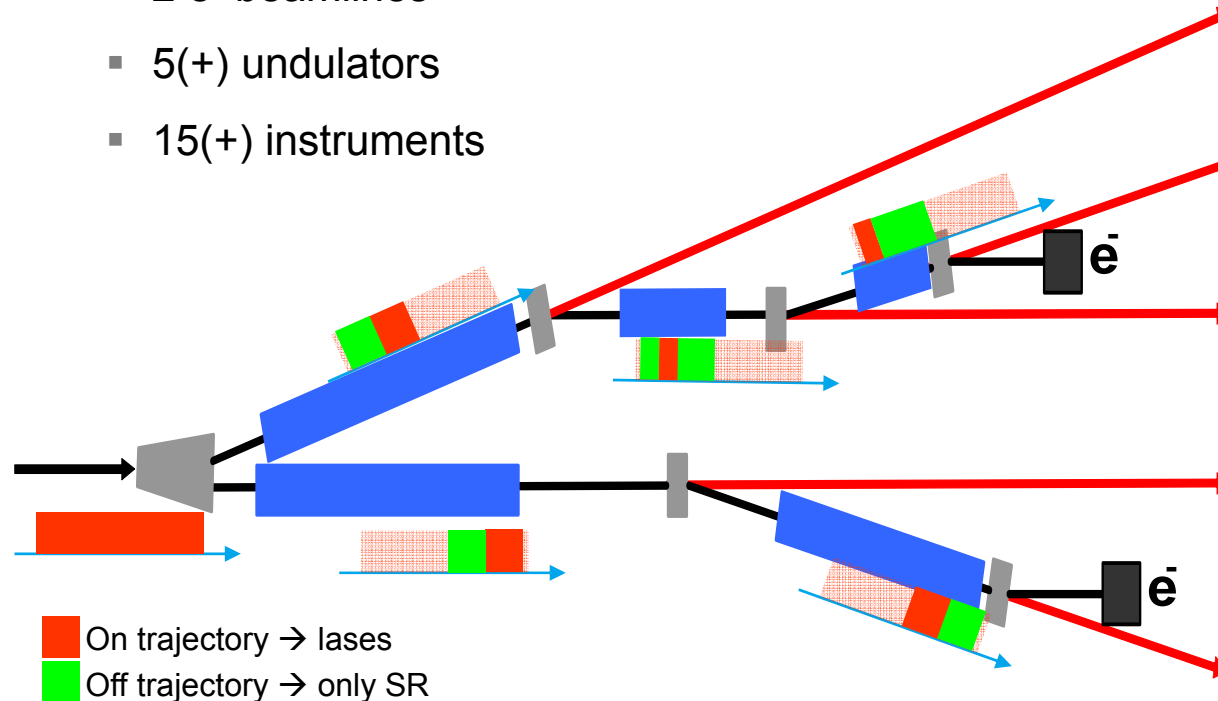
	Macro-pulse repetition rate	Macro-pulse length	Bunches per macro-pulse	Beam current during macro-pulse	Max bunches per second
LCLS	120 Hz	--	1	--	120
Spring8 XFEL	60 Hz		50		3000
Fermi@Elettra	10 Hz 50 Hz		1 1		10 50
super Fermi@Elettra	100 Hz		100		10000
European XFEL	10 Hz	650 μ s	2900 @ 4.5 MHz	4.5 mA	29000
FLASH	10 Hz	800 μ s	800 @ 1 MHz	1 mA	8000
BerlinPro ERL	1.3 GHz	cw	--	100 mA	$1.3 \cdot 10^9$
Cornell ERL	1 MHz 1.3 GHz	cw	--	1 mA 25/100 mA	$1.3 \cdot 10^6$ $1.3 \cdot 10^9$
ILC (RDR)	5 Hz	970 μ s	1000 - 5400	9 mA	5000 – 27000



EuXFEL: Simultaneous operation of many instruments

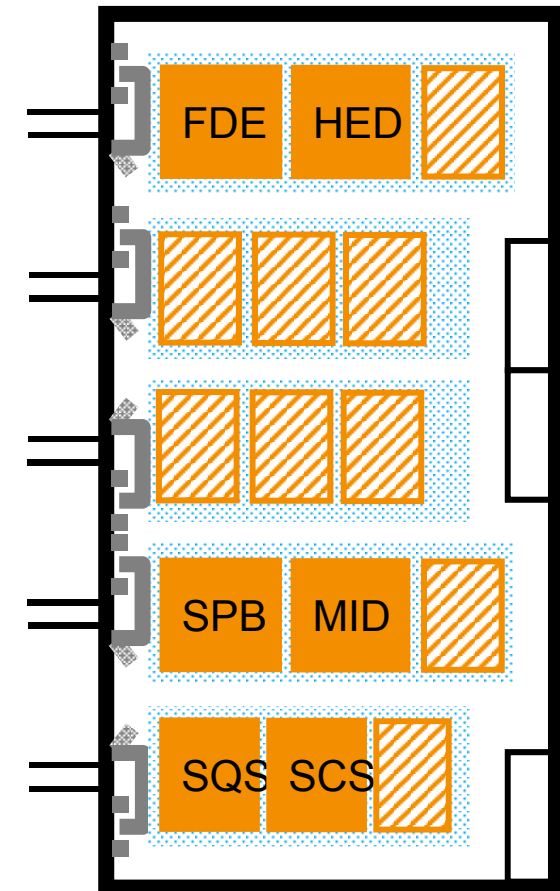
> Within the bunch train

- 2 e-beamlines
- 5(+) undulators
- 15(+) instruments



Sophisticated electron bunch distribution

- 27.000 bunches/sec to 5 beamlines
- in average 10-20 Hz and ~500 pulses/train
- using kicking methods to make bunches lase only in dedicated undulator



Boxes only placeholders !

Cathodes for Electron sources

	Macro-pulse repetition rate	Macro-pulse length	Max bunches per macro-pulse	single pulse energy	Wave-length	Cathode Type	Charge per second	QE
FLASH	10 Hz	800 μ s	800 @ 1 MHz	100 μ J IR 10 μ J UV	1047 \rightarrow 262 nm	Cs ₂ Te	8 μ C	10 %
European XFEL	10 Hz	650 μ s	2900 @ 4.5 MHz	100 μ J IR 10 μ J UV	1047 \rightarrow 262 nm	Cs ₂ Te	450 W	10 %
LCLS	120 Hz	--	--	20 mJ	800 \rightarrow 255 nm	Cu	--	<0.01 %
Fermi@ Elettra	10 Hz 50 Hz	--	--	20 mJ	800 \rightarrow 255 nm	Cu	--	< 0.01 %
BerlinPro ERL	1.3 GHz	--	--	1 μ J	550 nm	CsK ₂ Sb	--	10 %
Cornell ERL	1 MHz 1.3 GHz	--	--	10 μ J 1 μ J	800 nm	GaAs (?)	--	>10 %



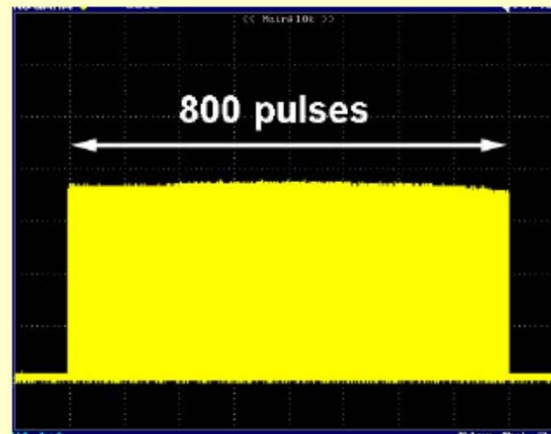
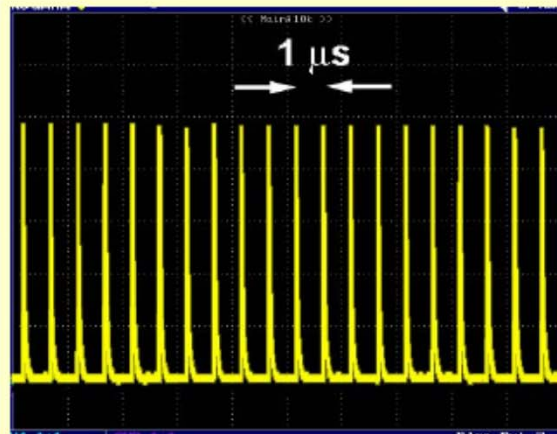
Lasers for Electron sources

	Macro-pulse repetition rate	Macro-pulse length	Max bunches per macro-pulse	single pulse energy	Wave-length	Laser Pulse length	Power in burst	Average power
FLASH	10 Hz	800 μ s	800 @ 1 MHz	100 μ J IR 10 μ J UV	1047 \rightarrow 262 nm	10 ps rms	100 W	0.8 W
European XFEL	10 Hz	650 μ s	2900 @ 4.5 MHz	100 μ J IR 10 μ J UV	1047 \rightarrow 262 nm	20 ps flat hat	450 W	3 W
LCLS	120 Hz	--	--	20 mJ	800 \rightarrow 255 nm	10 ps flat hat	--	2.4 W
Fermi@ Elettra	10 Hz 50 Hz	--	--	20 mJ	800 \rightarrow 255 nm	10 ps flat hat	--	1 W
BerlinPro ERL	1.3 GHz	--	--	1 μ J	550 nm	10 ps	--	1.3 kW
Cornell ERL	1 MHz 1.3 GHz	--	--	10 μ J 1 μ J	800 nm	?	--	10 W 1.3 kW



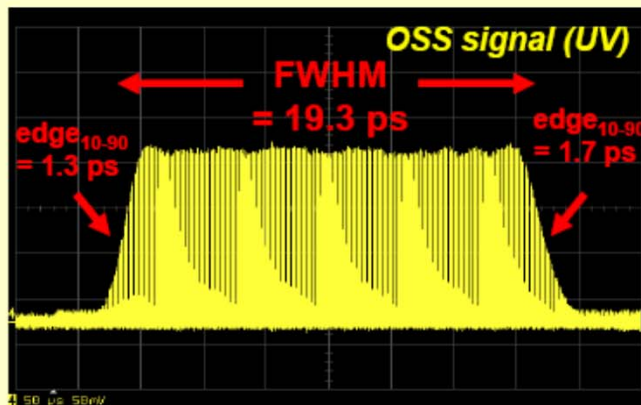
Example: FLASH/PITZ burst mode laser

- > State-of-the-art laser system for longitudinally flat hat pulses in burst mode
- > Challenge: upgrade from 1 MHz to 5 MHz bursts for the European XFEL



UV pulse trains containing up to 800 micropulses

I. Will, G. Klemz et al, MBI/DESY



Shape of the micropulses measured with the optical sampling system



Summary

- > Electron sources:
- > For high average power, we need cathodes with
 - high QE – to keep laser power reasonable
 - Operable in superconducting environment
- > For high QE cathodes, state-of-the-art lasers exists or are close to be finished for most sources
 - issue here is the requirements on shaping (transverse and longitudinal) in combination with high average power
 - Best would be a high QE for the lasers fundamental wavelength
 - For instance Ti:Sapphire / GaAs
 - Is GaAs operable in SC guns? What's about cesiation?
- > Low QE cathodes or high QE for non-fundamental laser wavelength are disfavored

